



FORM PTO-1449 (MODIFIED) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANTS INFORMATION DISCLOSURE STATEMENT	ATTORNEY DOCKET NO.	SERIAL NO.
	SP03-018	10/779582
	APPLICANT MACH J, et al.	
	FILING DATE 2/12/2004	GROUP: <u>2891</u> Unknown

REFERENCE DESIGNATION				U.S. PATENT DOCUMENTS			
Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date if Approp.
AICS	AA	4,294,602	10/13/81	Horne	65	40	
	AB	5,374,564	12/20/94	Bruel	437	24	
	AC	5,442,205	8/15/95	Brasen et al	257	191	
	AD	5,559,043	9/24/96	Bruel	437	24	
	AE	5,909,627	6/1/99	Egloff	438	406	
	AF	6,048,411	4/11/00	Henley et al	148	33.5	
	AG	6,107,653	8/22/00	Fitzgerald	257	191	
	AH	6,140,209	10/31/00	Iwane et al	438	458	
	AI	6,150,239	11/21/00	Goesele et al	438	458	
	AJ	6,211,041	4/3/01	Ogura	438	458	
	AK	6,251,754	6/26/01	Ohshima et al	438	506	
	AL	6,309,950	10/30/01	Forbes	438	455	
	AM	6,319,867	11/20/01	Chacon et al	501	66	
	AR	6,323,108	11/27/01	Kub et al	438	458	
	AS	6,335,231	1/1/02	Yamazaki et al	438	151	
	AT	6,391,740	5/21/02	Cheung et al	438	455	
	AU	6,573,126	6/3/03	Cheng et al	438	149	
AICS	AV	6,593,641	7/15/03	Fitzgerald	257	616	

FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Sub-Class	Translation Yes No
AICS	AW	EP0557588	9/1/93	Europe	93	35	X
AICS	AX	EP0539741	5/5/93	Europe	93	18	X

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)		
AICS	AY	M. Bruel; "Silicon on insulator material technology"; Electronics Letters; July 1995; Vol. 13, No. 14; pages 1201-1202
	AZ	Cioccio et al.; "Silicon carbide on insulator formation using the Smart Cut process"; Electronics Letters; June 1996; Vol. 32, No. 12; pages 1144-1145
	BA	Marshall et al; "Measurement of adherence of residually stressed thin films by indentation. I. Mechanics of interface delamination"; J. Appl. Phys; November 1984; Vol. 56, No. 10; pages 2632-2638
AICS	BB	Bister et al; "Ranges of the 0.3-2 MeV H ⁺ and 0.7-2 MeV H ₂ ⁺ ions in Si and Ge"; Radiation Effects; 1982; Vol. 59; pages 199-202.

Information Disclosure Statement-PTO-1449 (Modified)

Ashu Kumar Sarkar

9/14/05

AKS	BC	Lee, et al.: "Semiconductor layer transfer by anodic wafer bonding"; IEEE International SOI Conference; October 1997; Pages 40-41
AKS	BD	Spangler, et al.; "A technology for high-performance single-crystal silicon-on-insulator transistors"; IEEE Electron Device Letters; Vol. 8, No. 4; April 1987; pages 137-139

EXAMINER:

Asish Kumar Sanhar

DATE CONSIDERED:

9/14/05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609: draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449 (MODIFIED) LIST OF PATENTS AND PUBLICATIONS FOR APPLICANTS INFORMATION DISCLOSURE STATEMENT	ATTORNEY DOCKET NO. SP03-018	SERIAL NO. 10/779582
	APPLICANT James Gregory Couillard, et al.	
	FILING DATE February 12, 2004	GROUP: 2891

JUL 25 2005
 PATENT & TRADEMARK OFFICE

REFERENCE DESIGNATION			U.S. PATENT DOCUMENTS				
Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date if Approp.
AKS	AA	6537938	3-25-03	Myazaki	501	66	
AKS	AB	2002033189	3-21-02	Mascris	136	203	
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Sub-Class	Translation Yes No
	AL						
	AM						
	AN						
	AO						
	AP						
	AQ						

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)		
	AR	
	AS	
	AT	

EXAMINER: Asok Kumar Santhan DATE CONSIDERED: 9/14/05
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